

Micr -Stamping Method for Photoelectric Process

ABSTRACT OF THE INVENTION

064. This invention discloses a micro-stamping method for photoelectric process. First of all, in this invention, the micro-stamping method provides a stamp, an ink, an inkpad and a substrate, wherein the stamp or the inkpad having a specific raised pattern and the ink is one element of the group consisting of red ink, green ink and blue ink. Further, by adherence of the ink to the stamp, the specific pattern can be transferred to the surface of the substrate. Furthermore, this micro-stamping method comprises an ink adherence process, a positioning process, a pattern transferring process and a fixation process, and the above-mentioned processes will repeat until the three inks, such as red ink, green ink and blue ink, all adhered and fixed on the predetermined places of substrate. Moreover, this invention can be applied in the fabricating of color filters of TFT-LCD, emitting layers of OLED (Organic Light Emitting Diode) , emitting layers of PLED (Polymer Light Emitting Diode) or other related photoelectric processes. The representing figure of this invention is Fig. 1A.